

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)	MAIL STOP AF
Kazuya KAMON)	Group Art Unit: 1756
Application No.: 09/320,946)	Examiner: S. Mohamedulla
Filed: May 26, 1999)	Confirmation No.: 5658
For: PHOTOMASK, FABRICATION METHOD OF PHOTOMASK, AND FABRICATION METHOD OF SEMICONDUCTOR INTEGRATED CIRCUIT))))	

AMENDMENT UNDER 37 C.F.R. §1.116

This Amendment responds to the Office dated August 13, 2003 (Paper No. 23).

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Date: November 10, 2003

Please amend the above-identified application as follows:

11/12/2003 HDEMESS1 00000095 09320946 01 FC:1201 1118.00 OP

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